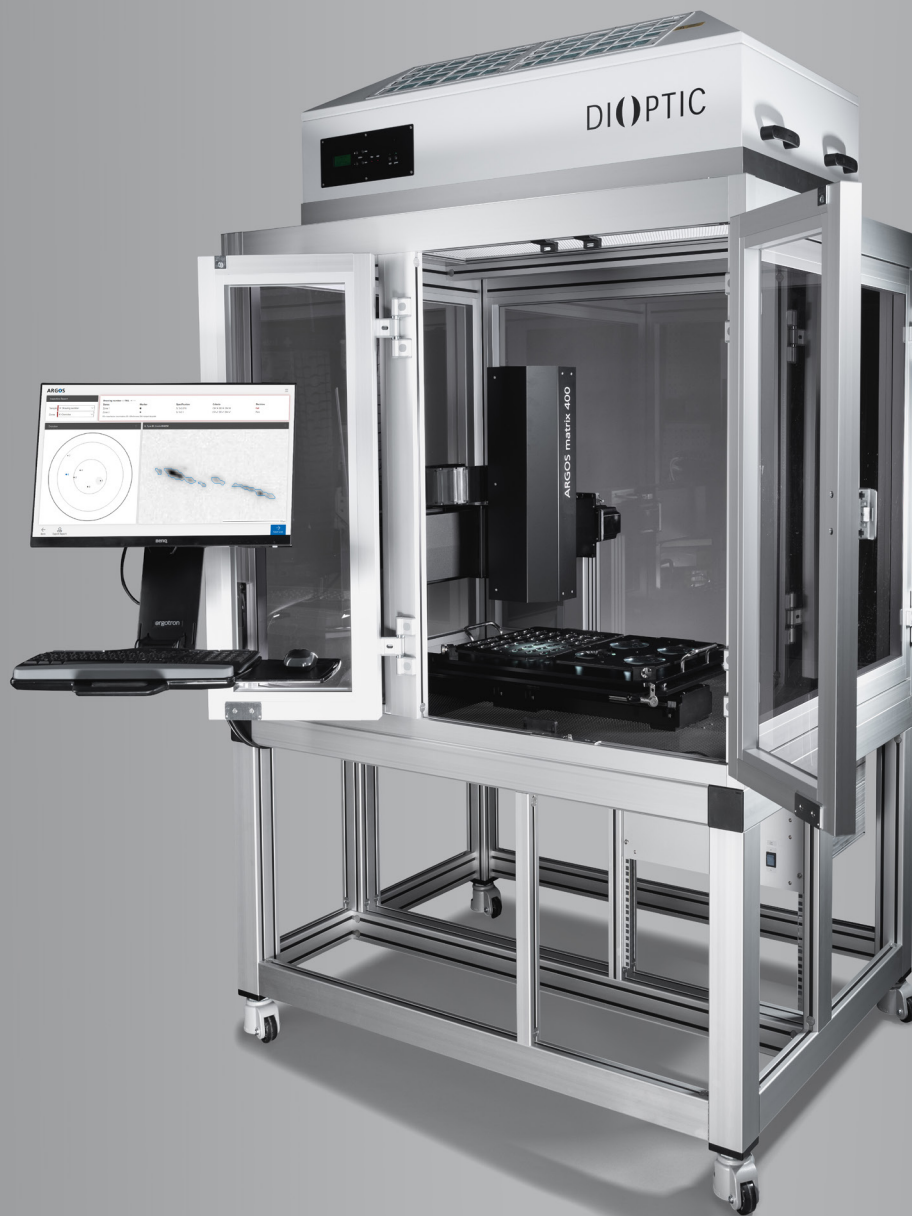


ARGOS matrix 400

automated scratch/dig inspection

DIOP_{TIC}
creating optical solutions



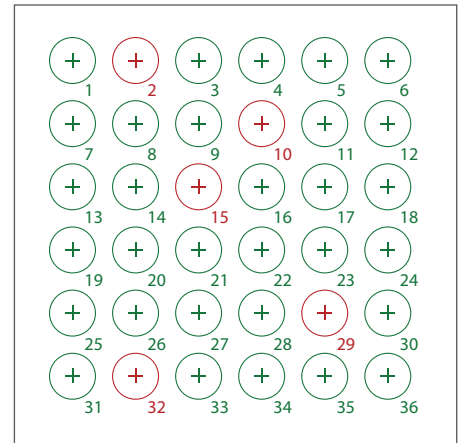
- FULLY AUTOMATED SURFACE INSPECTION
- VERSATILE FROM MICRO-OPTICS TO WAFERS
- OBJECTIVE AND REPRODUCIBLE



Automated stitching of large parts



Serial inspection of many parts on a tray



Clear pass/fail decision and detailed reports

BENEFITS

Large flexibility: any shape from aspheric micro lenses to 12" wafers can be inspected.

Automated serial inspection without user interaction reduces cost and improves process quality.

Objective test results with clear decisions and detailed information on relevant defects and statistics.

FUNCTIONALITY

ARGOS matrix 400 is equipped with a high-resolution camera and a switchable dark-field illumination. A precision 400x400mm stage allows inspection of either large numbers of parts or a single large surface - flat or curved.

PDF test reports with clear decision and detailed information are automatically created. The ARGOS matrix 400 is equipped with an integrated filter fan unit that ensures a laminar air flow in the system.

SPECIFICATIONS

ARGOS measurement head	ARGOS matrix S	ARGOS matrix M	ARGOS matrix L
Smallest ISO 10110-7 size grade	0.004 (digs), 0.0025 (scratches)	0.0063 (digs), 0.004 (scratches)	0.01 (digs), 0.0063 (scratches)
Smallest visible defects*	< 1 µm	< 2 µm	< 3 µm
Reproducibility of the size measurement*	< 1.5 µm	< 3 µm	< 4.5 µm
Inspection example* : 8" wafer	12 min	4 min	2 min
Inspection example* : Lens, D=30 mm, curvature R=30 mm	4 min	2 min	15s
Maximum inspection area / System size (LxWxH)	600x400 mm / 1510x1085x2322 mm		
Surface materials	Polished, uncoated or coated surfaces with optical quality, e.g. glass, semiconductors, metals, plastics, crystals, other surface types on request.		

*for details see technical specification document